

L Number	Hits	Search Text	DB	Time stamp
1	4	(micromechanical MEMS) same nitride with late adj transition adj metal	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/03/10 06:29
2	1	((micromechanical MEMS) same nitride with late adj transition adj metal) and @ad<20010623	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/03/10 06:36
3	4	(micromechanical MEMS) and nitride with late adj transition adj metal	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/03/10 06:34
4	8514	micromechanical MEMS	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/03/10 06:34
5	1715	(micromechanical MEMS) and (silicon boron) adj nitride	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/03/10 06:35
6	23	((micromechanical MEMS) and (silicon boron) adj nitride) and (ferromagnetic noble) adj metal?	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/03/10 06:36
7	16	((micromechanical MEMS) and (silicon boron) adj nitride) and (ferromagnetic noble) adj metal?) and @ad<20010623	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/03/10 06:38
8	20	((micromechanical MEMS) and (silicon boron) adj nitride) and (ferromagnetic noble) adj metal?) and (sensor? actuator?)	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/03/10 06:48
9	16	((micromechanical MEMS) and (silicon boron) adj nitride) and (ferromagnetic noble) adj metal?) and @ad<20010623 and @ad<20010623	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/03/10 06:50
10	2172	(micromechanical MEMS) same (sensor? actuator?)	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/03/10 06:48
12	0	((micromechanical MEMS) same (sensor? actuator?)) and (transition adj metal same (silicon aluminum boron) near2 nitride)) and @ad<20010623	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/03/10 06:53
11	2	((micromechanical MEMS) same (sensor? actuator?)) and (transition adj metal same (silicon aluminum boron) near2 nitride)	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/03/10 06:52

13	9	((micromechanical MEMS) and (transition adj metal same (silicon aluminum boron) near2 nitride))	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/03/10 06:58
14	4	((micromechanical MEMS) and (transition adj metal same (silicon aluminum boron) near2 nitride)) and @ad<20010623	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/03/10 06:58
15	12	((micromechanical MEMS) and (transition adj metal with nitride))	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/03/10 07:02
16	5	((micromechanical MEMS) and (transition adj metal with nitride)) and @ad<20010623	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/03/10 07:04
17	450	(transition adj metal with (silicon aluminum boron) adj nitride)	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/03/10 07:03
18	3	((transition adj metal with (silicon aluminum boron) adj nitride)) and MEMS	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/03/10 07:04
19	0	((((transition adj metal with (silicon aluminum boron) adj nitride)) and MEMS) and @ad<20010623	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/03/10 07:04
20	6	((transition adj metal with (silicon aluminum boron) adj nitride)) and micromechanical	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/03/10 07:04
21	4	((((transition adj metal with (silicon aluminum boron) adj nitride)) and micromechanical) and @ad<20010623	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/03/10 07:04